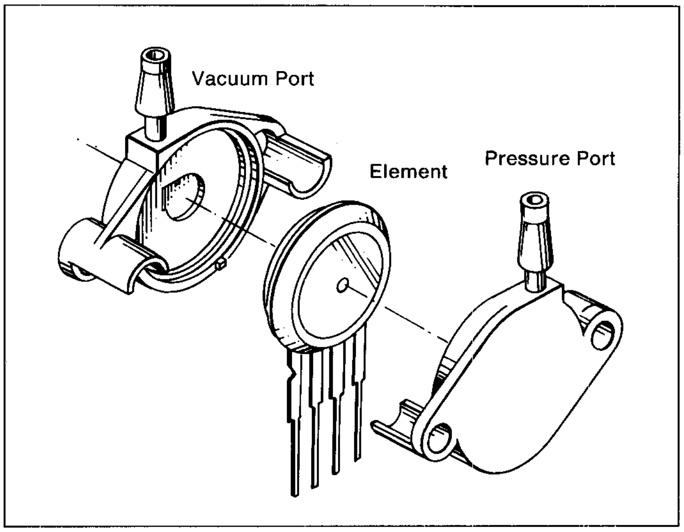
Pressure Sensors

A unique silicon shear stress sensitive piezoresistive element having an output that is ratiometric to the supply voltage. Devices are available with and without ported housings.



TWO BASIC ELEMENTS AND THREE PORTED PACKAGES

* Package Suffix	Packages
A	ABSOLUTE Element (zero kPa Reference Vacuum)
AP	ABSOLUTE Element with pressure side ported
D	DIFFERENTIAL Element
DP	DIFFERENTIAL Element with both sides ported
GP	DIFFERENTIAL Element with pressure sides ported
GVP	DIFFERENTIAL Element with vacuum side ported

FOUR PRESSURE RANGES

Device	Pressure Range		Full Scale Span Output	Offset	Sensitivity	Temperature Effect
	(PSI)	(mBars)	(mV)	(mV max)	(mV/PSI) Typ	On Full Scale Span (%/°C) Max
MPX10	0–15	0–100	20 to 50	35	24	−0.2
MPX2010*			25 to 26	±1.0	17	+0.01
MPX11			30 to 60	35	34	−0.2
MPX2011*			23 to 27	±2.0	17	+0.01
MPX12			45 to 70	35	38	−0.2
MPX50	0–7.5	0–500	45 to 90	35	8	−0.2
MPX2050*			38.5 to 41.5	±1.0	5.5	+0.01
MPX51			30 to 60	35	6	−0.2
MPX2051*			37.5 to 42.5	±2.0	5.5	+0.01
MPX52			30 to 90	35	8	−0.2
MPX100	0–15	0–1000	45 to 90	35	4	−0.2
MPX2100*			38.5 to 41.5	±1.0	2.8	+0.01
MPX2101*			37.5 to 42.5	±2.0	2.8	+0.01
MPX200	0–30	0–2000	45 to 90	35	2	−0.2
MPX2200*			38.5 to 41.5	±1.0	1.4	+0.01
MPX201			45 to 90	35	2	−0.2
MPX2201*			37.5 to 42.5	±2.0	1.4	+0.01

*These devices have internal temperature compensation.